

ElectriCont-G

AFM Tip

SHAPE	HEIGHT	SETBACK	RADIUS	HALF CONE ANGLE
Rotated	17 μm (15 – 19 μm)*	15 μm (10 – 20 μm)*	25 nm	20°–25° along cantilever axis, 25°–30° from side, 10° at the apex

AFM Cantilever

Cantilever A	
Shape	Beam
Force Constant	0.2 N/m (0.07 – 0.4 N/m)*
Resonance Frequency	13 kHz (9 – 17 kHz)*
Length	450 μm (440 – 460 μm)*
Width	50 μm (45 – 55 μm)*
Thickness	2 μm (1 – 3 μm)*

* typical range

Coating

Electrically conductive coating of 5 nm Chromium and 25 nm Platinum on both sides of the cantilever. This coating also enhances the laser reflectivity of the cantilever.

Alignment Grooves

This product features alignment grooves on the back side of the holder chip.

Additional Info

Monolithic silicon AFM probe for contact mode and lateral force mode operation and electric modes such as:

- scanning capacitance microscopy (SCM)
- scanning probe lithography

The rotated AFM tip allows for more symmetric representation of high sample features. The consistent AFM tip radius ensures good resolution and reproducibility.

The AFM holder chip fits most commercial AFM systems as it is industry standard size.